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(12) United States Patent Jin et al.

(54) PRINTED CIRCUIT BOARD AND PROBE

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THEREWITH

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(Continued)

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CPC A61B 8/4494 (2013.01); A61B 8/4461 (2013.01); A61B 8/4483 (2013.01); (Continued)

(58) Field of Classification Search

CPC A61B 8/00; A61B 8/4461; A61B 8/4483; A61B 8/4494; B06B 1/0622; H05K 1/189; H05K 2201/055; H05K 2201/09681; H05K 2201/09781; H05K 2201/10083; H05K 2201/10462; H05K 3/305 (10) Patent No.: US 9,462,996 B2

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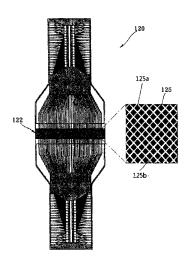
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(57) ABSTRACT

Probe includes a transducer, a PCB having a pattern part contacting the transducer via face-to-face contact, and a bonding member bonding the transducer to the pattern part of the PCB. The bonding part of the PCB is provided with the pattern part to increase a bonding area of the bonding part and to allow the bonding member to contact not only a metal layer of the bonding part but also an electrical insulation part thereof, thereby improving a bonding force between the transducer and the PCB. As a result, the transducer can be reliably bonded to the PCB, so that performance of the transducer can be prevented from being deteriorated due to defective connection between the PCB and the transducer.

14 Claims, 8 Drawing Sheets



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	2201/10462 (2013.01); Y02P 70/613	(2015.11) OTHER DURI ICATIONS

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Fig. 1

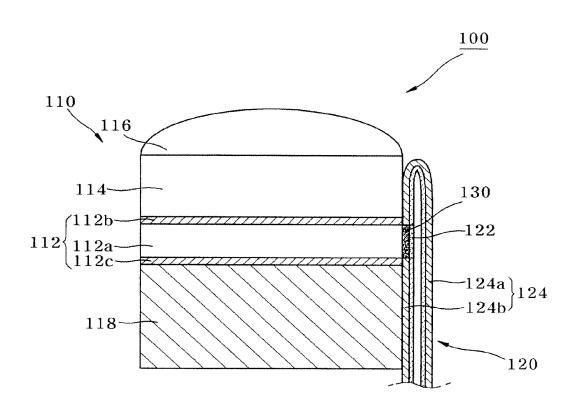


Fig. 2

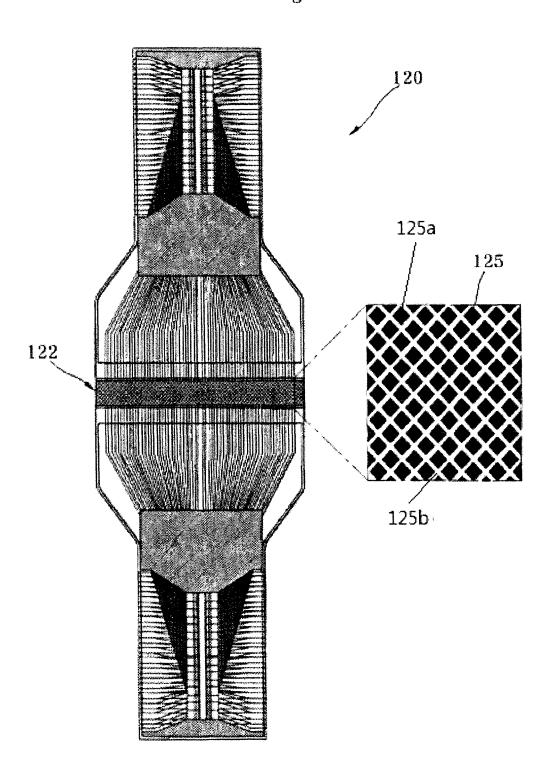


Fig. 3

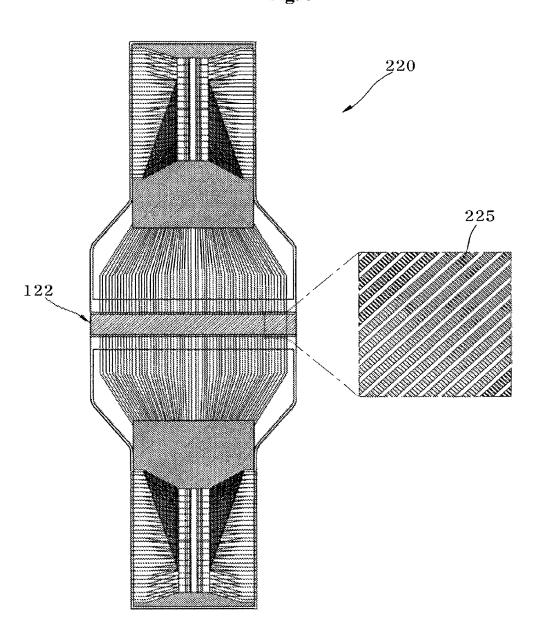


Fig. 4

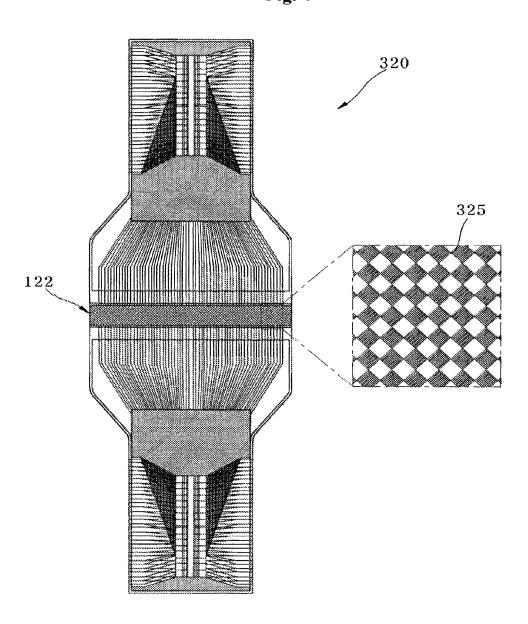


Fig. 5

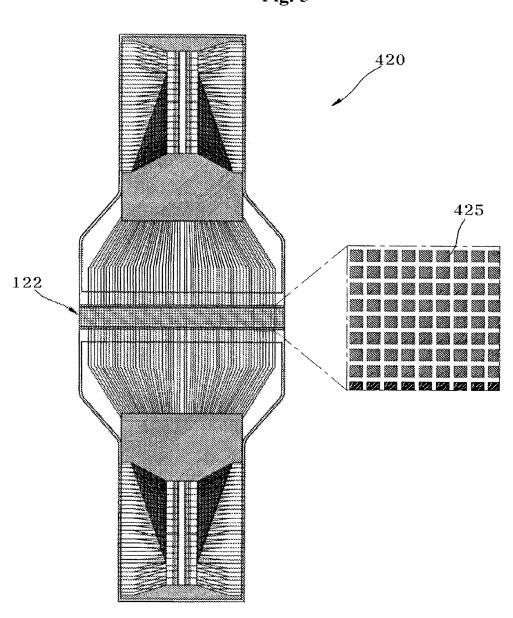


Fig. 6

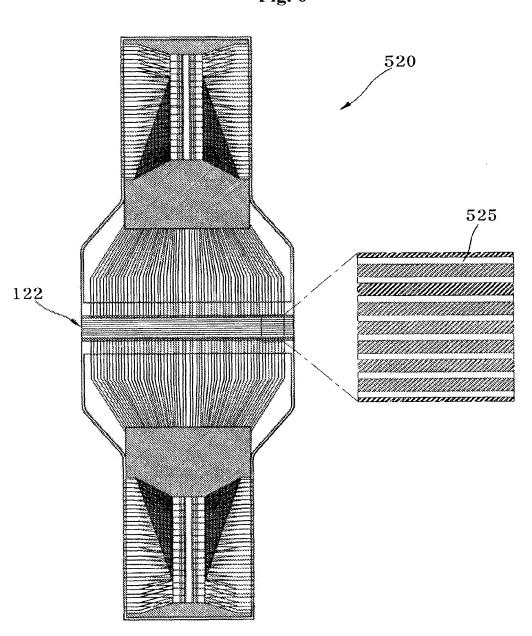
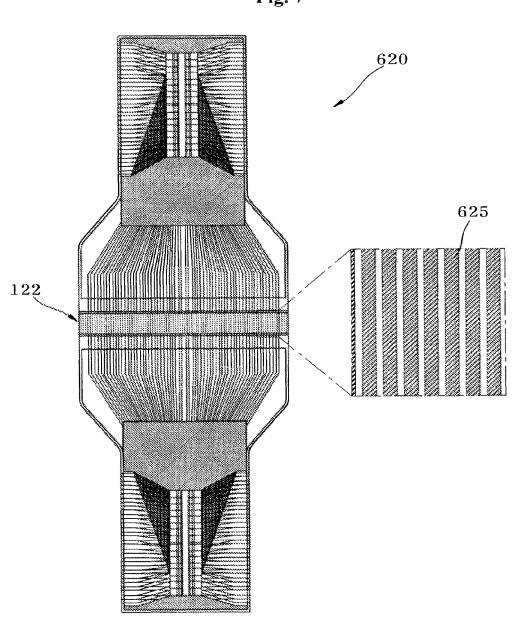


Fig. 7



712

716

714-

712a-712c-

718-

720

722
724a
724
724b
722

PRINTED CIRCUIT BOARD AND PROBE THEREWITH

CROSS-REFERENCE TO RELATED APPLICATIONS

This application is a Continuation of U.S. patent application Ser. No. 13/533,698, filed Jun. 26, 2012, which is a Continuation of U.S. application Ser. No. 12/607,571, filed on Oct. 28, 2009, now U.S. Pat. No. 8,228,681, issued Jul. 10 24, 2012, which claims the benefit of Korean Patent Application No. 10-2008-0106259, filed on Oct. 29, 2008, the entire contents of which are incorporated by reference herein.

BACKGROUND OF THE INVENTION

1. Field of the Invention

The present invention relates to a printed circuit board (PCB) and, more particularly, to a PCB and a probe includ- 20 ing the same for use in an ultrasound system that generates internal images of a patient body with ultrasound waves.

2. Description of the Related Art

Generally, an ultrasound system refers to a non-invasive apparatus that irradiates an ultrasound signal from a surface 25 of a patient body towards a target internal organ beneath the body surface and obtains an image of a monolayer or blood flow in soft tissue from information in the reflected ultrasound signal (ultrasound echo-signal). The ultrasound system has been widely used for diagnosis of the heart, the 30 abdomen, the urinary organs, and in obstetrics and gynecology due to various merits such as small size, low price, real-time image display, and high stability through elimination of any radiation exposure, as compared with other image diagnostic systems, such as X-ray diagnostic systems, 35 computerized tomography scanners (CT scanners), magnetic resonance imagers (MRIs), nuclear medicine diagnostic apparatuses, and the like.

Particularly, the ultrasound system includes a probe which transmits an ultrasound signal to a patient body and receives 40 the ultrasound echo-signal reflected therefrom to obtain the ultrasound image of the patient body.

The probe includes a transducer, a case with an open upper end, a cover coupled to the open upper end of the case to directly contact the body surface of the patient, and the 45 embodiments of the present invention; and

The transducer includes a piezoelectric layer in which a piezoelectric material converts electrical signals into sound signals or vice versa while vibrating, a coordination layer reducing a difference in sound impedance between the 50 piezoelectric layer and a patient body to allow as much of the ultrasound waves generated from the piezoelectric layer to be transferred to the patient body as possible, a lens layer focusing the ultrasound waves, which travel in front of the piezoelectric layer, onto a predetermined point, and a to 55 backing layer blocking the ultrasound waves from traveling in a rearward direction of the piezoelectric layer to prevent image distortion.

The piezoelectric layer includes a piezoelectric device, and signal and ground electrodes provided to upper and 60 lower ends of the piezoelectric device, respectively. Further, a PCB is bonded to the piezoelectric layer to be connected to the signal and ground electrodes in such a way that a bonding surface of the PCB is bonded to the ground electrode by an adhesive.

In such a probe, a bonding force between the piezoelectric device and the bonding surface of the PCB is low to cause 2

unreliable bonding between the PCB and the piezoelectric layer, thereby deteriorating performance of the probe. Therefore, there is a need for an improved probe that overcomes such a problem.

SUMMARY OF THE INVENTION

The present invention is conceived to solve the problem of the conventional technique as described above, and an aspect of the present invention is to provide an improved probe that can prevent deterioration of performance caused by defective connection between a piezoelectric layer and a printed circuit board (PCB).

In accordance with an aspect of the present invention, a probe includes: a transducer; a PCB having a pattern part contacting the transducer via face-to-face contact; and a bonding member bonding the transducer to the pattern part of the PCB.

The pattern part may include at least one of a polygonal pattern, a transverse line pattern, a lengthwise line pattern, an oblique line pattern, a circular pattern, an elliptical pattern, and a wave pattern.

The pattern part may include a convex portion.

The pattern part may include a concave portion.

In accordance with another aspect of the present invention, a PCB includes: a bonding part contacting an object via face-to-face contact; and a pattern part provided to the bonding part.

The pattern part may include at least one of a polygonal pattern, an oblique line pattern, a transverse line pattern, a lengthwise line pattern, a circular pattern, an elliptical pattern, and a wave pattern.

BRIEF DESCRIPTION OF THE DRAWINGS

The above and other aspects, features and advantages of the present invention will become apparent from the following description of exemplary embodiments given in conjunction with the accompanying drawings, in which:

FIG. 1 is a schematic cross-sectional view of a probe according to an embodiment of the present invention;

FIG. 2 is a view of a PCB shown in FIG. 1;

FIGS. 3 to 7 are views of PCBs according to various

FIG. 8 is a schematic cross-sectional view of a probe according to another embodiment of the present invention.

DETAILED DESCRIPTION OF THE **EMBODIMENT**

Exemplary embodiments of the present invention will now be described in detail with reference to the accompanying drawings. It should be noted that the drawings are not to precise scale and may be exaggerated in thickness of lines or size of components for descriptive convenience and clarity only. Furthermore, terms used herein are defined by taking functions of the present invention into account and can be changed according to the custom or intention of users or operators. Therefore, definition of the ten-ns should be made according to overall disclosures set forth herein.

FIG. 1 is a schematic cross-sectional view of a probe according to an embodiment of the present invention, and FIG. 2 is a view of a PCB shown in FIG. 1.

Referring to FIGS. 1 and 2, a probe 100 according to the embodiment of the invention includes a transducer 110, a PCB 120, and a bonding member 130.

The transducer 110 transmits an ultrasound signal to a patient body and receives the ultrasound echo-sound reflected therefrom. The transducer 110 includes a piezo-electric layer 112 in which a piezoelectric material converts electrical signals to sound signals or vice versa while 5 vibrating. The piezoelectric layer 112 includes a piezoelectric device 112a, which generates ultrasound waves through a resonance phenomenon, and signal and ground electrodes 112b and 112c provided to upper and lower ends of the piezoelectric device 112a respectively.

The piezoelectric device **112***a* may be formed of a ceramic of lead zirconate titanate (PZT), a PZNT single crystal made of a solid solution of lead zinc niobate and lead titanate, a PZMT single crystal made of a solid solution of lead magnesium niobate and lead titanate, or the like. 15 Further, the signal and ground electrodes **112***b* and **112***c* may be formed of a material having good electrical conductivity, such as gold, silver, or the like.

Further, the transducer 110 includes a coordination layer 114, which is formed of glass or resin materials and reduces 20 a difference in sound impedance between the piezoelectric layer 112 and the patient body so as to allow as much of the ultrasound waves generated from the piezoelectric layer 112 to be transferred to the patient body as possible, a lens layer 116 focusing the ultrasound waves, which travel in front of 25 the piezoelectric layer 112, onto a predetermined point, and a backing layer 118 blocking the ultrasound waves from traveling in a rearward direction of the piezoelectric layer 112 to prevent image distortion.

The PCB 120 is provided substantially perpendicular with 30 respect to the lamination direction of the transducer 110. An example of the PCB 120 is a flexible printed circuit board (FPCB). The PCB 120 includes a bonding part 122 and a line electrode part 124.

The bonding part 122 contacts the piezoelectric layer 112 35 of the transducer 110, more specifically, a lateral side of the piezoelectric device 112a of the piezoelectric layer 112. The bonding part 122 includes a flexible electrical insulation film, and a metal layer formed on the electrical insulation film.

The line electrode part 124 includes a signal line electrode 124a and a ground line electrode 124b. The signal line electrode 124a and the ground line electrode 124b are disposed corresponding to the signal electrode 112b and the ground electrode 112c of the piezoelectric layer 112, respectively. The signal line electrode 124a and the ground line electrode 124b are soldered to the signal electrode 112b and the ground electrode 112c by a solder such as lead or the like, respectively, thereby electrically connecting the piezoelectric layer 112 to the PCB 120.

On the other hand, the bonding part 122 is bonded to the lateral side of the piezoelectric device 112a via a bonding member 130. The bonding member 130 is made of a non-conductive material to insulate the signal electrode 112b from the ground electrode 112c while bonding the piezoelectric device 112a to the bonding part of the PCB 120. The bonding member 130 may be an adhesive deposited between the bonding part 122 and the piezoelectric device 112a to form a bonding layer therebetween. Bonding between the bonding part 122 and the piezoelectric device 112a allows 60 the PCB 120 to be bonded to the transducer 110.

The bonding part 122 is provided with a pattern part 125. The pattern part 125 is partially formed on the bonding part 122 or is formed over the entire surface of the bonding part 122. The pattern part 125 is provided to be in face-to-face 65 contact with the piezoelectric layer 112 when the PCB 120 is bonded to the piezoelectric layer 112. The pattern part 125

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is formed by etching the metal layer formed on the electrical insulation film of the bonding part 122 such that the electrical insulation film can be exposed in a predetermined shape.

According to this embodiment, the pattern part 125 is illustrated as including a predetermined pattern, more specifically, a rhombus pattern. The rhombus pattern may be formed in a convex portion 125a or a concave portion 125b on the bonding part 122. Here, the convex portion 125a corresponds to a portion where the metal layer is formed, and the concave portion 125b corresponds to a portion where the electrical insulation film is exposed.

In the probe 100 of this embodiment, the pattern part 125 is provided to the bonding part 122 of the PCB 120 bonded to the piezoelectric device 112a, as described above, so that the bonding part 122 has an increased bonding area and the bonding member 130 can come into contact with not only the metal layer of the bonding part 122 but also the electrical insulation film thereof, thereby enhancing the bonding force between the transducer 110 and the PCB 120.

In the probe 100 according to this embodiment, the transducer 110 and the PCB 120 can be more reliably bonded to each other, thereby preventing performance deterioration of the probe 100, which can be caused by defective connection between the transducer 110 and the PCB 120.

In the above description, the pattern part 125 is illustrated as including the rhombus pattern, but the present invention is not limited thereto.

FIGS. 3 to 7 are views of PCBs according to various embodiments of the present invention.

For convenience of description, the same or similar configurations as those of the above embodiment will be indicated by the same reference numerals, and detailed descriptions thereof will be omitted herein.

Referring to FIGS. 3 to 7, PCBs 220, 320, 420, 520 and 620 may have a pattern part 225 including an oblique line pattern as shown in FIG. 3, a pattern part 325 including a polygonal pattern of a rhombus shape as shown in FIG. 4, a pattern part 425 including a polygonal pattern of a rectangular shape as shown in FIG. 5, a pattern part 525 including a transverse line pattern as shown in FIG. 6, and a pattern part 625 including a lengthwise line pattern as shown in FIG. 7, respectively. Additionally, although not shown in the drawings, the pattern part may be realized in various modifications including a circular pattern, an elliptical pattern, a wave pattern, and the like.

FIG. **8** is a schematic cross-sectional view of a probe according to another embodiment of the present invention. Referring to FIG. **8**, a probe **700** according to this embodiment includes a transducer **710** and a PCB **720**.

In FIG. 8, the transducer 710 includes a piezoelectric layer 712, a coordination layer 714, a lens layer 716, and a backing layer 718. The piezoelectric layer 712, coordination layer 714, lens layer 716, and backing layer 718 are stacked to constitute a laminate. The configuration and operation of the transducer 710 are similar to those of the transducer 110 (see FIG. 1) according to the above embodiment, and a detailed description thereof will be omitted.

The PCB **720** is provided substantially in the horizontal direction with respect to the lamination direction of the transducer **710**, and includes a bonding part **722** and a line electrode part **724**.

The bonding part **722** contacts an upper or lower side of a piezoelectric layer **712**. The bonding part **722** includes a flexible electrical insulation film, and a metal layer formed on the electrical insulation film.

The line electrode part 724 includes a signal line electrode 724a and a ground line electrode 724b. The signal line electrode 724a and the ground line electrode 724b are disposed corresponding to a signal electrode 712b and a ground electrode 712c of the piezoelectric layer 712, respectively. The signal line electrode 724a and the ground line electrode 724b are soldered to the signal electrode 712b and the ground electrode 712c by a solder such as lead or the like, respectively, thereby electrically connecting the piezoelectric layer 712 to the PCB 720.

On the other hand, the bonding part **722** is bonded to the upper or lower side of the piezoelectric layer **712** via a bonding member (not shown). The bonding member bonds the bonding part **722** of the PCB **720** to the piezoelectric layer **712**. The bonding member may be a non-conductive adhesive deposited between the bonding part **722** and the piezoelectric layer **712** to form a bonding layer therebetween. Bonding between the bonding part **722** and the piezoelectric layer **712** allows the PCB **720** to be bonded to the transducer **710**.

The bonding part 722 is provided with a pattern part (reference numeral omitted). The pattern part is partially formed on the bonding part 722 or is formed over the entire surface of the bonding part 722. The pattern part is provided to be in face-to-face contact with the piezoelectric layer 712 when the PCB 720 is bonded to the piezoelectric layer 712. The pattern part is formed by etching the metal layer formed on the electrical insulation film of the bonding part 722 such that the electrical insulation film of the bonding part can be exposed in a predetermined shape. The configuration and operation of the pattern part are similar to those of the pattern parts 125, 225, 325, 425, 525 and 625 shown in FIGS. 2 to 7, and a detailed description thereof will be omitted herein.

As apparent from the above description, according to the embodiment of the present invention, a bonding part of the PCB is provided with a pattern part to increase a bonding area of the bonding part and to allow a bonding member to contact not only a metal layer of the bonding part but also an electrical insulation part, thereby improving a bonding force between a transducer and the PCB. As a result, the transducer can be reliably bonded to the PCB, so that performance of the transducer can be prevented from being deteriorated due to defective connection between the PCB and the transducer.

Although the present invention has been described with reference to the embodiments shown in the drawings, it will be apparent to those skilled in the art that the embodiments are given by way of illustration only, and that various modifications and equivalent embodiments can be made without departing from the spirit and scope of the present invention. Accordingly, the scope of the present invention should be limited only by the accompanying claims.

What is claimed is:

- 1. A probe, comprising:
- a transducer including a signal and ground electrode;
- a printed circuit board (PCB) having an uneven portion contacting the transducer via face-to-face contact; and 60
- a bonding member made of a non-conductive material and bonding the transducer to the uneven portion of the PCB.
- wherein the uneven portion includes a metal layer and an electrical insulation film,
- the metal layer is disposed on the electrical insulation film, and

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- the electrical insulation film includes a first portion which is exposed in a predetermined shape through the metal layer and a second unexposed portion.
- 2. The probe according to claim 1, wherein the uneven portion has one of shapes among a polygonal shape, a transverse line shape, a lengthwise line shape, an oblique line shape, a circular shape, an elliptical shape, and a wave shape.
- 3. The probe according to claim 1, wherein the uneven portion comprises a convex portion.
 - **4**. The probe according to claim **1**, wherein the uneven portion comprises a concave portion.
 - 5. The probe according to claim 1, wherein the transducer includes:
 - a piezoelectric layer having a piezoelectric device, wherein the signal electrode and ground electrode are respectively disposed on a top surface and a bottom surface of the piezoelectric device;
 - a backing layer disposed on a bottom surface of the piezoelectric layer:
 - a coordination layer disposed on a top surface of the piezoelectric layer; and
 - a lens layer disposed on a top surface of the coordination layer, the top surface being opposite to a surface of the lens layer facing the coordination layer.
- 6. The probe according to claim 5, wherein the bonding member is attached to the piezoelectric device of the piezoelectric layer.
 - 7. A probe, comprising:

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- a transducer including a piezoelectric layer, a signal electrode, and a ground electrode;
- a printed circuit board (PCB) having at least one bonding part, the at least one bonding part being inserted in the transducer in parallel with the extending direction of the piezoelectric layer, and the at least one bonding part facing a top surface or a bottom surface of the piezoelectric layer respectively, wherein at least one bonding part has an uneven portion contacting the bottom surface or top surface of the piezoelectric layer; and
- a bonding member made of a non-conductive material and bonding the transducer to the uneven portion of the PCB.
- wherein the uneven portion includes a metal layer and an electrical insulation film,
- the metal layer is disposed on the electrical insulation film, and
- the electrical insulation film includes a first portion which is exposed in a predetermined shape through the metal layer and a second unexposed portion.
- 8. The probe according to claim 7, wherein the at least one bonding part includes two bonding parts facing the bottom and top surfaces of the piezoelectric layer respectively.
- 9. The probe according to claim 8, wherein the transducer includes:
 - a piezoelectric layer having a piezoelectric device, wherein the signal electrode and ground electrode are respectively disposed on a top surface and a bottom surface of the piezoelectric device;
 - a backing layer disposed on a bottom surface of the piezoelectric layer;
 - a coordination layer disposed on a top surface of the piezoelectric layer; and
 - a lens layer disposed on a top surface of the coordination layer, the top surface being opposite to a surface of the lens layer facing the coordination layer.
- 10. The probe according to claim 9, wherein the two bonding parts are inserted between the piezoelectric layer

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and the backing layer and between the piezoelectric layer and the coordination layer respectively.

- 11. The probe according to claim 10, wherein a signal line electrode and a ground line electrode are disposed inside the two bonding parts and facing the signal electrode and the 5 ground electrode respectively.
 12. The probe according to claim 10, wherein each of the
- 12. The probe according to claim 10, wherein each of the two bonding parts includes a metal layer and an electrical insulation film inside the metal layer.
- 13. The probe according to claim 10, wherein the uneven 10 portion is formed on a portion of each of the two bonding parts facing the piezoelectric layer.
- 14. The probe according to claim 10, wherein the uneven portion is formed on entire portion of the each of the two boding parts facing the piezoelectric layer.

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